

# Index

The following abbreviations are used within the index

|      |                                   |      |   |
|------|-----------------------------------|------|---|
| EMMA | Electron microscope microanalyser | SIM  | Secondary ion emission microscope         |
| EPM  | Electron probe microanalysis      | STEM | Scanning-transmission electron microscope |
| FEM  | Field-emission microscope         | TEM  | Transmission electron microscope          |
| FIM  | Field-ion microscope              | THEM | Thermionic emission microscope            |
| PEM  | Photo-emission microscope         | XRT  | X-ray topography                          |
| SEM  | Scanning electron microscope      |      |   |

*Bold type indicates the main reference.*

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